# Observation of the whole Thomson scattering spectrum for diagnostics of EUV and Soft X-ray light source plasmas

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# Introduction

- > EUV and Soft X-ray (SXR) radiation (electron transition) profiles from high-Z plasmas strongly depend on electron temperature  $(T_e)$ , density  $(n_e)$ , and ionic charge (Z)<sup>[1]</sup>.
- > Using collective Thomson scattering (CTS) technique, we are trying to measure  $n_{\rm e}$ ,  $T_{\rm e}$ , and Z of EUV and SXR light source plasmas. <sup>[3-5]</sup>



**Thomson scattering for SXR sources** 

- $\succ$  Higher Z (>20) from heavier element are needed for shorter wavelength (< 13.5 nm) light sources.
- $\succ$  In this case, the ion component is not sufficient to determine  $n_{\rm e}$ ,  $T_{\rm e}$ , and Z because of a lack of <u>spectral shape</u> information (ion acoustic wave is not strongly dumped).
- $\succ$  Then, we have fabricated customized spectrometers to detect the whole Thomson scattering spectrum (the ion and the electron components).





### **Previous studies** - Thomson scattering for EUV sources -

To measure *n*e, *T*e, and *Z* simultaneously, we have applied laser **collective Thomson** scattering (CTS) to laser-produced EUV light source plasmas (<u>Droplet Sn +CO<sub>2</sub> laser</u>). CTS consists the ion component and the electron component. In the previous studies, we have fabricated a special spectrometer having 6 gratings, and successfully detected the ion



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# **Problems to detect electron component**

- Very different spectral width and intensity
  - fabricate two spectrometers
- 2. Weak signal intensity
  - concentrate to detect the <u>peak wavelength</u> of the electron component.
  - to subtract large self-emission correctly, measured spectrum was divided in two parts (emission w/ or w/o TS) using polarization of TS.

 $\lambda = 1064 \text{ nm}$ 

300 mJ/pulse

8ns duration

# Experiment





1D profiles of  $n_{e}$  and  $T_{e}^{[3]}$ 

EUV

#### 1.3 μs-plasma 2.0 μs-plasma 2.5 μs-plasma CE:4.0% (C) image um -200 -200 200 -200 200 200 0 0 0 1.E+26

- $n_{\rm e}$  and  $T_{\rm e}$ (m<sup>-3</sup>) 1E+24 Hullac code [1] -200 200 -200 200 -200 1.2E+16 1.2E+16 1.2E+16 1E+16 1E+16 1E+16 8E+15 8E+15 Emissivity 6E+15 6E+15 6E+15  $(W/m^3/eV/$ 4E+15 4E+15 4E+15 sr) -200 200 -200 200 0 200 -200 x (µm)

 $\checkmark$  The CEs of the three types of plasmas differed (2.8 to 4.0%). ✓ The spatial profiles of  $n_{\rm e}$  and  $T_{\rm e}$ ,

were clearly changed with the delay time between the pre- and main lasers

- However, under all plasma conditions, intense EUV was only observed at a sufficiently high  $T_{\rm e}$  (>25 eV) and in an adequate  $n_{\rm e}$  range  $[10^{24} - (2$  $\times 10^{25}$ ) m<sup>-3</sup>].
- These plasma parameters lie in the efficient-EUV light source predicted by range, as simulations<sup>[1]</sup>.



 $\lambda = 532 \text{ nm}$ 

80 mJ/pulse

8ns duration



1<sup>st</sup> results <sup>[5]</sup>

 $\lambda = 1064 \text{ nm}$ 

250 mJ/pulse

8ns duration

As the first step, we used Sn plasmas and measured the electron component.



# **2D** profiles of $n_e$ and $T_e$ <sup>[4]</sup>

![](_page_0_Figure_38.jpeg)

In the 1.3 µs-plasma,  $\checkmark$ the high  $n_{\rm e} (> 4 \times 10^{24})$ m<sup>-3</sup>) and the high  $T_e$ (25 eV) regions were clearly separated. In the 2.5 µs-plasma,  $n_{\rm e}$  is too low.

In the 2.0 µs-plasma, the regions of the high  $n_{\rm e}$  and the high  $T_{\rm e}$ largely overlapped in directions (the both path axis and laser radial axis). A hollowlike density profile was observed.

#### **B** 0 peak width $(T_e, T_i, Z)$ shape $(n_e, I_e)$ 10 15 $\Delta\lambda$ (pm) $\Delta\lambda$ (nm)

enables to determine 4 parameters of LPP-EUV plasma.

### Conclusions

- > 2D-spatial profiles and temporal evolutions of ne, Te, and Z of EUV light sources (Sn droplet + CO<sub>2</sub> laser) were revealed using collective Thomson scattering. In this case, only the ion component was observed.
- $\blacktriangleright$  To measure  $n_{\rm e}$ ,  $T_{\rm e}$ , and Z of the SXR light sources, whose Z > 20, observation of the whole Thomson scattering spectrum (the ion and the electron components) are necessary.
- > As the first step, the whole CTS spectrum was observed from Sn plasmas and the four parameters  $(n_{\rm e}, T_{\rm e}, T_{\rm i}, \text{ and } Z)$  were determined simultaneously.

#### References

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"Observation of the whole Thomson scattering spectrum of laser-produced plasmas for EUV light"